

Form PTO 1449  
(Modified)U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTY DOCKET NO.

240896US2S

SERIAL NO.

NEW APPLICATION

## LIST OF REFERENCES CITED BY APPLICANT

APPLICANT

Naofumi NAKAMURA, et al.

FILING DATE

HEREWITH

7/29/03

GROUP

2815

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
Mew	AA	6,291,891	09/18/01	Kazuyuki HIGASHI, et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO
	AO				
	AP				
	AQ				
	AR				
	AS				
	AT				
	AU				
	AV				

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

Mew	AW	Kelly H. BLOCK, et al., "Integration of CMP with Low-k Materials", SEMICONDUCTOR INTERNATIONAL, June 2002, pgs. 115-122			
	AX				
	AY				
	AZ				

☐ Additional References sheet(s) attached

Examiner

Matthew M

Date Considered

12/1/04

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.